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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 2786**  
Kazuto HIROKAWA et al. : Docket No. 2001-1050A  
Serial No. 09/910,907 : Group Art Unit 3723  
Filed July 24, 2001 : Examiner Maurina T. Rachuba

POLISHING TOOL AND  
MANUFACTURING METHOD THEREFOR

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**STATEMENT OF SUBSTANCE OF INTERVIEW**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The following is in response to the requirement as set forth in the Interview Summary form mailed July 15, 2004 pursuant to the interview between Primary Examiner Maurina Rachuba and the undersigned.

Examiner Rachuba is again thanked for her courtesy in granting and conducting the interview of July 12, 2004.

In the interview, it was briefly discussed how the claims as amended in the response filed June 22, 2004 overcome the rejection based on James et al., U.S. 6,069,080. A specific discussion of the distinctions was not made in view of the Examiner's ready indication that the amendment overcomes the rejection under 35 U.S.C. 102. The Examiner mentioned that a further rejection under 35 U.S.C. 103 would be considered, but no specific indication of how such a rejection might be made was indicated. The undersigned, further, briefly indicated that support

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

for the claims as now presented could be found in the specification beginning at about page 30 thereof, and with reference to Fig. 7, for example. Also, the Examiner's attention is directed lines 6-12 of page 32 of the specification.

Respectfully submitted,

Kazuto HIROKAWA et al.

By: 

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